

PSS直徑光學量測系統

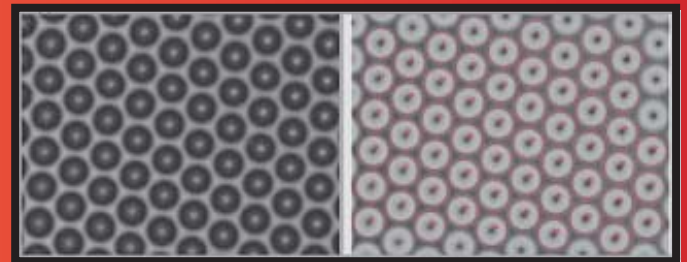
Auto Dimension Measurement System

PHi-200

性能表現 超乎想像



Force reserves the right to make changes and improvements to this product.



	Dimension
Max	2.767um
Min	2.668um
Average	2.715um

自有技術 來自台灣

Specification 產品規格

Inspection Objective	Magnification: 100X
Sample Size	2 inch and 4 inch
Sample Stage	Type A: 4" Type B:Cassette in/cassette out.
Inspection Area	Center of each wafer, one point per wafer or programmable for multi-site measurements
Dimension Analysis	Automatic calculation for both PSS and PR(ADI) wafer
Computer System	CPU: 1GHz; RAM: 2GB; USB 2.0
Vibration isolation	Embedded Vibration isolator
Power	100 - 240 VAC, 50/60Hz, 100W
Temperature Range	25±2 °C
Humidity Range	≤ 70%, non-condensing

Note: Performance specifications are typical and subject to change without notice.
Visit our website for most up-to-date specifications.

Feature 產品特色

- 可快速量出PSS結構之寬度數據。
- 可選擇單片人工操作或robot 取放片方式。
- 可自動對焦與自動計算直徑，避免人為誤差。
- 數據可依照SEM結果進行校正，正確可靠。
- 同時適用於光阻片與PSS片。
- 無探針之損耗。
- 適合產線量產使用，可真正達到片片全檢之量測。

Components 系統包含

- 高倍率物鏡
- LED燈源
- 單片手動方式或卡匣In/ Out之裝載方式
- 控制用電腦
- 底寬計算軟體